

METHOD FOR FABRICATING LARGE AREA FLEXIBLE ELECTRONICS

by

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I. BACKGROUND OF THE INVENTION

1. Cross reference to related application:

This application is a continuation in part of USSN 09/728,639 filed November 29, 2000.

2. Field of the Invention

This invention relates generally to a method for placement of individual elements, including pixels, on a new substrate.

The subject of this invention is a method for the transfer and placement of individual elements or devices fabricated on a semiconductor substrate to predetermined locations in a new substrate of any material, shape and size, as well as in-situ electrical monitoring to make sure that all elements have been

properly placed in these locations.

More particularly, the invention comprises a method by which individual elements are epitaxially lifted off a seed substrate and placed in predetermined and arbitrary circular holes, or receptors, on a new substrate.

### 3. Description of the Related Art.

In the prior art, the positioning of individual elements into predetermined locations in a new substrate (following the lifting these individual elements off the original seed substrate) is achieved using submersion of these elements and the new substrate into a fluid and allowing the fluid flow to transfer the elements to the receptor sites.

The liquid submersion method has three key drawbacks:

(1) the liquid submersion of the individual elements and the new substrate precludes the use of in-situ electrical monitoring for the realtime determination of the correctness of placement of the individual elements in the receptors;

(2) the liquid submersion also precludes the placement of various adhesives for the proper electrical attachment of the individual elements to the receptors; and

(3) the square-shaped elements and receptors described for this method are inadequate because the possibility is reduced that they be placed in the receptors correctly.

Another method for transferring individual elements fabricated on one substrate to different locations on a new substrate comprises transferring these elements to a stretchable membrane via the epitaxial liftoff process, followed by stretching the membrane to position and bond the circuit elements to their new locations. Following this bonding, the membrane layer is then released.

The obvious disadvantage of the stretchable membrane technique is the inability to position the individual elements to any arbitrary location on the new substrate due to the limitations of the stretchable membrane. Also this technique involves a double transfer process in which the circuit elements are first attached to the membrane before being stretched and bonded to the new substrate, thus decreasing the fabrication yield.

There is a need for a method for transferring individual elements fabricated on one substrate to different locations on a new substrate without the drawbacks and disadvantages described above. The present invention discloses such a method, and the individual elements can be transferred to any arbitrary location on the new substrate as well as checked in-situ for their proper electrical placement before the final bonding as described below.

## II. SUMMARY OF THE INVENTION

The present invention is directed to a method used to lift individual elements off a seed substrate and to place these individual elements in receptors on the new substrate, using gravitational forces and vibrational energy.

The present invention is also directed to the technique used for realtime electrical verification of whether the placement of these elements in the receptors is correct. The realization of this concept allows transfer of electrical circuitry fabricated on an original substrate to a new substrate made of any material, and having any shape and size. One such example would be the realization of large area active matrix circuits on flexible substrates for displays as described hereinafter.

The method also allows the transfer of devices or circuits fabricated on a substrate made of one type of material to a substrate made of a different type of material. For instance, using this method, arrays of microelectromechanical switches (MEMS) operating in the radio-frequency regime together with their associated integrated electronics can be transferred to a large flexible antenna aperture.

Another example of particularly beneficial application of this invention pertains to the technology of large area active matrix displays. Millions of active matrix driver pixels can be prefabricated on a silicon substrate using conventional foundry processing, and then transferred to a large sheet of glass or plastic substrate as described in detail below. Flexible and

conformal displays for automobiles are yet other examples of application of the method of this invention.

One of the main advantages of the method of this invention is the realization of large area electronics on flexible and lightweight plastic carriers (such as large area flexible active matrix displays) with the circuits or devices prefabricated on a crystalline semiconductor substrate (such as silicon). According to a competing technology, the devices and circuitry are fabricated on plastic carriers by means of deposited polycrystalline semiconductors which have inferior electrical characteristics compared to those fabricated on single crystal silicon. The proposed technology of this invention is superior to the competing technology mentioned above

The circuit elements are epitaxially lifted off a seed substrate first. Then, using gravitational force and vibrational energy in a controlled environment, the circuit elements are allowed to slide down the new substrate raised from one end at a predetermined and preferably, at an optimum angle. The circuit elements lifted off the original seed substrate are preferably in the shape of a truncated cone for easy placement in holes in the new substrate which also have the same matching shape.

The resulting circular symmetry allows easy placement of the circuit elements in the receptors independent of their lateral orientation. The subsequently described unique concentric ring-shaped electrode pattern and its circular symmetry allows easy placement of the elements into the receptors and proper electrical contact between them, independent of their lateral orientation,

when they arrive at these sites compared to the square-shaped elements and receptors known in prior art because the shape of square reduces the possibility of the correct placement of the elements in these sites.

Conductive interconnection between the individual elements and the new substrate is achieved by contact between circularly symmetric terminations on the bottom of each element and their corresponding connections prefabricated on the new substrate inside the receptors. Using these interconnections, the electrical contact between each circuit element and other circuitry prefabricated on the new substrate can be electrically verified in real time as the individual elements fall into the receptors.

In one aspect, the present invention provides a method for transferring circuit elements originally supported by an original substrate to locations on a new substrate. This method comprises steps of: providing said original substrate with a release member disposed upon a surface of said original substrate, said circuit elements being fabricated on top surface of said release member; defining individual elements about said circuit elements, said individual elements preferably having a conical frustum-shaped configuration; fabricating a first set of electrically conductive contacts on a surface of said individual elements, said first set of electrically conductive contacts being preferably concentrically disposed rings defining space therebetween; freeing said conical frustum-shaped individual elements by removing said release member; defining frustum-shaped individual element receptors in said new substrate, said receptors having a bottom surface and sloping side walls, said receptors being sized to

receive said conical frustum-shaped individual elements;  
fabricating a second set of electrically conductive contacts on  
said bottom surface, said second set of electrically conductive  
contacts being concentrically disposed rings defining space  
therebetween, said second set of electrically conductive contacts  
arranged so as to match said first set of electrically conductive  
contacts when one of said frustum-shaped individual elements is  
received in ne of said frustum-shaped individual element  
receptors; applying an electrically conductive substance inside  
said receptors so as to cover at least the electrically conductive  
contacts on said bottom surface of said receptors, said  
electrically conductive substance exhibiting increased  
conductivity in a direction normal to said bottom of said  
receptors; raising said new substrate to an incline, with one end  
of said new substrate being higher than an opposite end of said  
new substrate; pouring said freed frustum-shaped individual  
elements onto the higher end of the surface of said new substrate  
having said receptors and shaking said new substrate so that free  
frustum-shaped individual elements fall or roll down the inclined  
new substrate and are received in said receptors and said rings of  
said first set of electrically conductive contacts being brought  
into conductive contact with corresponding rings of said second  
set of electrically conductive contacts by the electrically  
conductive substance inside said receptors; and removing  
unreceived and/or improperly received frustum-shaped individual  
elements which have fallen or rolled down to said opposite end of  
the inclined new substrate from said surface of said new  
substrate.

In another aspect, the present invention provides a method for

transferring individual elements fabricated on an original substrate to arbitrary predetermined locations on a new substrate, the method comprising steps of providing said original substrate with a release member disposed upon a surface of said original substrate, said individual elements having been fabricated on top surface of said release member; forming circular individual elements surrounding said individual elements; shaping said individual elements to assume a frustum shape; fabricating a first set of electrically conductive contacts on top of a smaller circular surface of said frustum, said first set of electrically conductive contacts being concentrically disposed rings defining space therebetween; freeing said conical frustum-shaped individual elements by removing said release member; providing a new substrate having conical frustum-shaped individual elements receptors, said receptors having an inside area defined by a curved inside wall, a top circular opening on a surface of said new substrate, and an inside circular surface, said inside circular surface being defined as the bottom of said receptors, said top circular opening being disposed oppositely to said inside circular surface, said top circular opening having a diameter larger than a diameter of said inside circular surface, said receptors having a volume of said inside area larger than a volume of said conical frustum-shaped individual elements; fabricating a second set of electrically conductive contacts on said inside circular surface, said second set of electrically conductive contacts being concentrically disposed rings defining space therebetween, said second set of electrically conductive contacts arranged so as to match said first set of electrically conductive contacts; applying and partially curing an electrically conductive resin inside said receptors so as to cover only said bottom of



said receptors; raising said new substrate to an incline, with one end of said new substrate being higher than an opposite end of said new substrate; pouring said freed conical frustum-shaped individual elements onto the higher end of the surface of said new substrate having said receptors followed by shaking said new substrate so that said freed conical frustum-shaped individual elements roll down the inclined new substrate and are trapped inside said receptors and said rings of said first set of electrically conductive contacts being in contact with corresponding rings of said second set of electrically conductive contacts; removing untrapped and/or improperly trapped conical frustum-shaped individual elements that have rolled down to said opposite end of the inclined new substrate from said surface of said new substrate and placing said untrapped conical frustum-shaped individual elements onto said surface of said new substrate; repeating said shaking followed by said step of removing until all said receptors are filled with said conical frustum-shaped individual elements and completing said curing of said electrically conductive resin inside said receptors.

Another aspect of the invention provides a method for monitoring and correcting following the transferring of the individual elements, the method for monitoring and correcting comprising steps of applying voltage pulse waveforms to the second set of metallization contacts; measuring a current pulse generated as a result of applying of the voltage pulse waveforms and repeating the steps of applying of the voltage pulse waveforms and of measuring of the current pulse with each receptor.

### III. BRIEF DESCRIPTION OF THE DRAWINGS

The features and advantages of the present invention will be better understood with regard to the following description, appended claims, and accompanying drawings where

FIG. 1 is a schematic diagram showing truncated cone-shaped circuit elements formed on top of a release layer.

FIG. 2 is a schematic diagram showing truncated cone-shaped circuit elements formed on top of a release tape.

FIG. 3 is a schematic diagram showing concentric ring-shaped electrodes formed on the top surface of the circuit elements.

FIG. 4 is a schematic diagram showing predefined circular receptors in new substrate with matching ring contacts.

FIG. 5 is a schematic diagram showing Z-axis epoxy for vertical contact between the contact rings in the receptors and on the elements.

FIG. 6 is a schematic diagram showing an inclined position of a substrate for transfer of the circuit elements aided by vibrational energy.

FIG. 7 is a schematic diagram showing two-transistor active matrix circuit for driving LEDs.

FIG. 8 is a schematic diagram showing row and column voltage and current pulses for verifying proper electrical contact between the

circuit elements and the receptors.

#### IV. DETAILED DESCRIPTION OF THE EMBODIMENTS OF THE INVENTION

Disclosed is a method for placing individual devices or circuit elements fabricated on a substrate (hereinafter an "original substrate" or a "seed substrate") in predetermined locations on another substrate (hereinafter a "new substrate"), and a method for in-situ electrical monitoring of whether these elements are correctly placed in the their new location. These methods are described in detail below.

First, the device or circuit elements are fabricated on an original substrate using conventional device and circuit fabrication processes. These fabrication processes are known to those skilled in the art. The each device or circuit element could comprise, by way of one example, a pixel display element.

In a preferred embodiment, a release layer 1 is disposed on top of original substrate 2, and the device or circuit elements are fabricated on top of the release layer 1, as shown in FIG. 1. For example, a silicon-on-insulator (SOI) substrate is preferably used as an original substrate 2, and the device or circuit elements are fabricated on such SOI substrate, where a silicon oxide layer beneath an active top silicon layer would serve as the sacrificial release layer 1.

Alternatively, a group III-V semiconductor substrate can also be used, provided an etch-stop layer is first deposited between the

device layer and the substrate layer. Manufacturing of such etch-stop layer is conducted according to common methods known to those skilled in the art. An illustration of such etch-stop layer can be an AlAs etch-stop layer sandwiched between a gallium arsenide substrate and a gallium arsenide device layer.

The method which is the subject of the present invention, described in detail hereinbelow, will remain the same for both the preferred SOI substrate and for the alternative group III-V semiconductor substrate or even if the substrate is not a semiconductor material.

Following the fabrication of the device or circuit elements 3, circular individual elements around these elements are formed via standard lithographic and dry etching techniques in order to isolate the individual elements. Dry etching is the preferred technique for realizing the truncated cone shaped individual elements subsequently described. The etching method used is preferably an isotropic etching.

For the purposes of this invention, the term "circular individual elements" means "individual elements having a shape with a generally circular cross-section."

The isotropic etching of the original substrate 2 between the device or circuit elements leads to the formation of individual elements 3 in the shape of a truncated right circular cone, preferably, conical frustum as shown in FIG. 1. Individual elements 3 can be manufactured of any size which may be required in a particular application. As the lateral dimension of

individual elements is increased, their thickness is also increased proportionally, so that when the individual elements 3 are released from the original substrate 2, as subsequently described, they would not curl up. A ratio of the lateral diameter of an individual circuit element 3 to its thickness is preferably within a range of between about 10:1 and about 50:1.

If the device or circuit elements are fabricated on top of a release layer 1, the truncated cone-shaped elements 3 are confined between the top surfaces of the device layer and the release layer 1.

If the entire bulk of the seed substrate 2 is etched to define the isolated individual elements 3 without the presence of a release layer 1, a temporary carrier is first attached to the original substrate 2, using a removable adhesive. A solid black wax is a preferred removable adhesive, Apiezon Wax W manufactured by M&I Materials, Ltd. of Manchester, United Kingdom, being the more preferred removable adhesive. Any material inert to the etching solution is suitable to be used as the temporary carrier.

Etching of the entire bulk of the seed substrate 2 is particularly preferred when the individual elements 3 have large lateral diameters, in order to decrease the ratio between the lateral diameter and the thickness of the individual circuit element 3 and thus to improve the mechanical stability of the latter.

Alternatively, instead of the temporary carrier, a release tape 4 can be first attached to the original substrate 2, as shown in FIG. 2

Following the formation of truncated-cone shaped individual elements 3, electrically conductive contacts or electrodes (preferably metallization contacts or electrodes in the form of concentric rings) are fabricated on these elements in order to provide subsequent electrical contact of the devices or circuits form on these individual elements 3 to a new substrate.

Standard metal deposition methods may be used to form the electrically conductive contacts, such as deposition by evaporation or sputtering followed by etching using a photolithographic mask. These methods are common and well known to those skilled in the art. Non-oxidizing metals are preferred materials to fabricate the metallization contacts, gold being more preferred metal. Alternatively, other standard metals used to fabricate integrated circuits, such as aluminum or titanium-tungsten, are also acceptable metals and can be used likewise. Additionally, non-metal electrically conductive materials may also be used, if desired.

These ring-shaped electrodes preserve the circular symmetry of the individual circuit element 3 so as to make subsequently described placement of the individual circuit element 3 in the receptors 10 easy. In one embodiment of this invention, where active matrix array pixels for displays are formed on elements 3 and transferred to a new substrate 9, four concentric contact rings (comprising a row connection contact ring 5, a column connection contact ring 6, a display element connection contact ring 7, and a ground connection contact ring 8) are formed on the top surface of the individual elements as shown in FIG. 3. Of course, other applications may well require different numbers or types of

contacts 5-8.

Following the fabrication of the electrically conductive contacts 5-8, the release layer 1 or temporary carrier, or the release tape 4 is removed, thus freeing the truncated cone-shaped individual elements 3 containing the individual device or circuit elements formed thereon and/or therein.

In case of the SOI material comprising the original substrate 2, the release layer 1 is the oxide layer beneath the active layer, as mentioned above. The release layer 1 is preferably etched in a buffered solution of hydrofluoric acid, according to standard etching techniques known to those reasonably skilled in the art, to release the predefined individual elements 3.

The new substrate 9, into which these individual elements 3 will be finally placed, comprises truncated cone-shaped receptors 10 having the same general shape of truncated cones as the individual elements 3 which the receptors 10 will receive. Generally speaking, the receptors 10 are slightly bigger, preferably, between about 5% to about 10% bigger, dimensions to accommodate the individual elements 3, as shown in FIG. 4. The larger circular plane of the truncated cone-shaped receptor forms an opening in the surface of the new substrate, and the smaller circular surface faces the inside of the receptor.

The new substrate onto which the individual elements 3 are transferred can be of any size or shape. The new substrate can be made of any material, for instance, another semiconductor material, various kinds of glass or plastic suitable for flexible

electronic uses. The receptors 10 are formed in the new substrate by a variety of methods, comprising, but not limited to, etching, stamping and laser machining.

Electrically conductive contacts, preferably in the form of concentric rings 11-14, are also formed inside the receptors 10 in the new substrate 9, the electrically conductive contacts matching the electrically conductive contacts formed in the individual elements 3 described above, as seen in FIG. 4.

Shown in FIG. 4 are the four concentric contacts 11-14 for the embodiment mentioned above (in which embodiment active matrix array pixels for displays are formed and transferred), these four concentric electrodes 11-14 formed inside the truncated cone-shaped receptors in a special pattern to avoid crossing of the electrodes.

The concentric contact ring 11 matches the ground contact 8, the concentric ring 12 matches the display contact 7, the concentric ring 13 matches the column contact 6, and the concentric ring 14 matches the row contact 5.

It is clear from FIG. 4 that the contacts 11-14 mate with respective contacts 5-8. Crossing portions, which are depicted at right angles to the concentric ring contacts 11-14 in FIG. 4, are preferably used to connect the ring contacts 11-14 with other appropriate circuitry or metalization (not shown) via respective connection members 11a - 14a. Where the connection members 12a - 14a cross a ring with which they are not coupled, they should, of course, be insulated therefrom. Silicon dioxide, for example, may



be used for this purpose and indeed the tops and sides of the crossing portions may be covered with silicon dioxide so that they can pass underneath such rings without making a connection thereto (a detail not shown in the figures). Silicon dioxide can be deposited in appropriate insulating locations using methods known to those skilled in the art.

Contacts 11-14 are fabricated inside the receptors 10 using standard processes, for example, for metal pattern fabrication known to those skilled in the art. These processes comprise metal deposition via evaporation and sputtering followed by lithographically defined pattern for wet or dry etching.

The contacts 11-14 continue to the top surface 15 of the new substrate 9 connecting them to other circuitry or metallization formed on this surface 15. For this particular embodiment, these continuations 11a, 12a, 13a, and 14a of the rings 11-14 are formed on the surface 15, as shown on FIG. 4.

After the contacts 11-14 are formed, a conductive material 16, and preferably a Z-axis conductive epoxy 16, is placed in the receptors 10. As shown on FIG. 5, the conductive epoxy only needs to create a conductive circuit between respective contacts 11-14 in the receptors 10 and respective contacts 5-8 on the elements 3. Since the conductive material or epoxy 16 typically will not simply stay put on the ends of the contacts 11 - 14, but will much more likely spread over the bottom of the receptors, in order to keep the conductive material or epoxy 16 from shorting adjacent concentric contacts to one another, a material or epoxy which is conductive uni-dimensionally is preferably used with the uni-

dimensional conductive direction of material 16 or epoxy 16 being arranged normal to the bottom surface 17 of the receptors 10. Such uni-dimensionally conductive epoxies are known and are identified as having Z-axis conductivity. Commercially manufactured Z-axis conductive epoxy resins are available from Zymet Corporation, and the resin ZXUV-102 manufactured by Zymet Corporation is a preferred Z-axis conductive epoxy resin.

The thickness of Z-axis epoxy resin 16 is determined by the diameter of the metallic (or metal coated polymer) microspheres suspended in the resin. The diameter of said microspheres is preferably within a range of between about 5 micrometers and about 12 micrometers. After the individual elements 3 have fallen properly into their receptors 10, as subsequently discussed, with the Z-axis epoxy resin in between, slight pressure applied on a circuit element 3 helps establish an electrical contact between the ring electrodes 5-8 and their corresponding counterpart contacts 11-14. Such electrical contact helped to be established through the conductive particles contained within the Z-axis epoxy resin 16 when the respective contacts 11-14 in a given receptor 10 fail to make physical contact with their respective contacts 5 - 8 on an element 3 which has fallen therein.

One method of applying this slight pressure is by using the pressure from the inert gas 20 inside the enclosure where the assembly is placed, as discussed below.

Both the top surface 15 covered with photoresist and the inside of the receptors 10 of the new substrate 9 are initially coated with this Z-axis epoxy 16 and then, using a photoresist liftoff

technique, the excess epoxy is removed and the Z-axis epoxy 16 is retained only inside the receptors 10, mainly on the bottom surfaces 17 of the receptors and perhaps with some epoxy 16 on the side walls thereof. Standard photoresist liftoff techniques known to those skilled in the art are used. Alternatively, a stenciling technique can be used to deposit the Z-axis epoxy only in the receptors 10.

The Z-axis epoxy 16 is preferably applied by a method of automatic dispensing using a moving epoxy dispenser. This method allows to achieve uniform coverage of the epoxy both inside and outside the receptors. Alternatively, the Z-axis epoxy can be applied by other methods, such as stenciling or spraying. The preferred method of curing is by ultra-violet radiation. Alternatively, for substrates blocking the ultra-violet radiation, thermal curing can be used.

The Z-axis epoxy 16 comprises small gold-coated spherically shaped polymers embedded inside an epoxy material with low enough concentration, preferably between about 500 and about 2,500 spheres per square millimeter, of these spheres to result in conductivity only in the vertical direction (Z-axis), thus preventing the ring electrodes from shorting laterally. The Z-axis epoxy 16 is therefore electrically insulating in the lateral (X and Y-axis) directions.

There is only one microsphere (embedded in the matrix resin) between the two contacting surfaces in the vertical direction, that is, between the ring electrodes and corresponding contacts on the receptors 10, after compressing pressure of between about 0.5 and about 1.0 gram per particle is applied. The diameter of one

sphere determines the distance between the two contacting surfaces.

The Z-axis epoxy 16 enables vertical contact between the concentric ring-shaped contacts 5-8 of the individual elements 3 and the contacts 11-14 of the receptors 10 without shorting the contacts 5-8 and 11-14 laterally.

Once the conical frustum-shaped individual elements 3 are separated from each other by removing the release layer 1, they are removed from (for example by shaking off) the original substrate 2, collected in a container (not shown) and are placed along one side of the new substrate 9, as shown in FIG. 6, followed by pouring of the individual elements 3 onto the new substrate 9.

A fraction of these individual elements 3 will land on their smaller diameter side while the rest land on the side with the larger diameter as the elements are dropped on the side of the new substrate 9 which is raised to an optimum incline angle, preferably between about  $30^{\circ}$  and about  $60^{\circ}$ , as shown on FIG. 6.

By preferably applying an appropriate vertical vibrational (for example, ultrasonic) energy to assist their movement in the direction 17, the truncated cone-shaped individual elements 3 slide or roll down the ramped new substrate 9 and gradually fill up the receptors 10 if positioned in the right orientation (the large diameter side facing up). Such vibrational energy can be obtained using any appropriate commercially available ultrasonic generator. Alternatively, vibrations having non-ultrasonic

frequencies can be used.

Once the free individual elements 3 that have not filled any receptor 10 site reach the bottom of the ramp, they are recycled and transferred, preferably by a motorized mechanism 18, to the top of the ramp 19 to start a new cycle of sliding down the ramp 19 to fill up the remaining empty receptors 10, as shown on FIG. 6.

By utilizing a greater number of individual elements 3 (for example, five to ten times greater) than the total number of receptors 10 on substrate 9, and by recycling the untrapped individual elements, all the empty receptors 10 will be filled after a few cycles. The circularly symmetric shape of the receptors 10 and that of the individual elements 3 allows easy filling of the holes independent of the lateral orientation of the elements when they approach the receptor sites. The entire assembly is placed inside an enclosure filled with a small flow of an inert gas 20 (such as nitrogen) to provide a controlled environment for this individual circuit element transfer and placement process.

Of course, the shape of the elements 3 and the receptors 10 in cross section may be non-circular, but if non-circular elements 3 and receptors 10 are utilized, that will decrease the likelihood of an element 3 correctly falling into an empty receptor 10 and this increase the amount of time for the filling of the receptors. However, non-circular elements 3 and receptors 10 might be desired in some applications where the elements 3 must be oriented in a particular orientation (or in one of several different particular

orientations) relative to the substrate 9. Absent such a need, the elements 3 and the receptors 10 are preferably circular or near-circular in cross section in a plane taken parallel to surface 15.

Another aspect of this invention relates to a technique for real-time monitoring and verification of the correct filling of the receptors 10 with the conical frustum-shaped individual elements 3. According to this technique, voltage pulse waveforms are externally applied to the lines 11a-14a on the top surface 15 of the new substrate 9 connecting to the concentric ring electrodes 11-14 inside the receptors 10. The resulting measured current pulse between these electrodes 11-14 and a common electrode contacting the individual elements, such as ground electrode, is an indication of electrical contact between a ring electrode and its corresponding contact point on the individual circuit element.

This voltage pulse waveform is sequentially applied to the electrodes of all the receptor sites 10 with their corresponding current pulse monitored throughout the period of the cyclic travel of the individual elements 3 down the ramp 19.

In the case where the individual elements 3 fall into the receptors 10 at a wrong angle preventing intimate contact of electrodes 5-8 fabricated in the individual elements 3 with the corresponding electrodes 11-14 inside the receptors 10, these individual elements 3 are shaken out of the receptors 10 by applying an appropriate vibrational energy and recycling them for proper placement. This vibrational shaking should not affect the individual elements 3 that have fallen properly into the receptors

and hence are contacting the Z-axis epoxy 17 due to the surface tension as well as the sticky nature of the epoxy.

The technique described above is general and applies to individual elements 3 with any circuit configuration formed thereon. For a particular embodiment of this invention described above (where the individual elements 3 are active matrix circuits for driving display elements, such as organic LEDs or LCDs), this testing technique is shown schematically in FIG. 7. In this embodiment, a two transistor active matrix circuit for driving LEDs, described above, there are four concentric ring contacts for the row 5 (select), column 6 (data), display element drive 7, and ground electrodes 8, as shown in FIG. 3.

Matching ring contacts 11-14 are also formed inside the receptor sites 10 connecting to the row 5, column 6, display 7, and ground 8 ring electrodes of the individual circuit element. Two voltage pulse waveforms 23 and 24a - 24c are applied to the row 14a and column 13a lines sequentially addressing each individual circuit element 3 in the display. The individual circuit element also comprises a switching transistor 21 and a drive transistor 22. The resulting switching transistor 21 drain current pulse measured in the column 6 line of the individual circuit element 3 is a confirmation of proper contact between the row 5, column 6, and ground 8 terminals of that individual circuit element 3 and their corresponding terminals 11, 12 and 14 inside the receptor 10.

For example, the first row is activated with a voltage pulse waveform 23, as shown in FIG. 8. Column pulse voltages 24a-24c are then applied to each column of the display sequentially within the

duration of the row pulse waveform as shown on FIG. 8. The current pulse 25a-25c flowing through each column terminal (and ground or common terminal) is measured during the time frame of that column pulse waveform. Only three column pulse waveforms are shown on FIG. 8 for the purposes of illustration. Generally, any number of columns and corresponding number of column pulse waveforms can be used.

Voltage applied to row electrodes is higher than the threshold voltage of the switch transistor 21. Voltage applied to the column electrodes is preferably within a range of between 2 Volts and about 5 Volts.

The duration of the pulse waveform applied to the row electrodes ( $T_{row}$ ) is the time for one cycle of the individual elements, sliding down the ramp in the attempt to fall into the receptors, divided by the number of row electrodes. The period of the row pulse is the time of one such cycle.

The duration of the pulse waveform applied to the column electrodes is  $T_{row}$  divided by the number column electrodes. The period of the column pulse is again the time of one cycle mentioned above.

The presence of this current 25a - 25c is a verification that the three terminals (column, row and ground) of that individual circuit element confined by the said row and column are making proper contact to their counterparts in the receptor. This process is continued for all the columns, and hence individual elements,